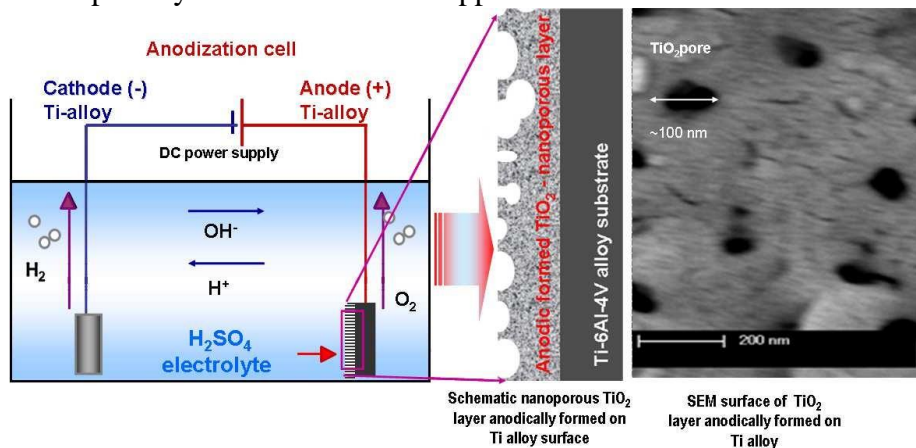


High Voltage Source for Oxide Films Formation TDK LAMBDA 28294



- 100-300V, current 0-8A
- Oxide film controlled formation
- Electrochemical Processes for surface anodizing at high voltage (100-300V)
- Auxiliary Outputs, 5V, 0.2A; 15V, 0.2A For Increased System Control Functionality
- RoHS Compliant
- High Power Density 2.4kW in 1U
- Wide Range of popular worldwide AC inputs, 1Ø (230VAC) & 3Ø (208VAC)
- Active Power Factor Correction (Single-Phase & Three-Phase AC Input)
- Built-in RS-232/RS-485 Interface Standard
- Global Commands for Serial RS-232/RS-485 Interface
- Auto-Re-Start / Safe-Start: user selectable
- Last-Setting Memory
- High Resolution 16 bit ADCs & DACs
- Low Ripple & Noise
- Front Panel Lock selectable from Front Panel or Software
- Reliable Encoders for Voltage and Current Adjustment
- Constant Voltage/Constant Current auto-crossover
- Parallel Operation with Active Current Sharing; up to four identical units.
- Advanced Parallel Master / Slave. Total Current is Programmed and Measured via the Master.
- Independent Remote ON/OFF and Remote Enable/Disable
- External Analog Programming and Monitoring (user selectable 0-5V & 0-10V)
- Reliable Modular and SMT Design
- 19" Rack Mount capability for ATE and OEM applications



Schematic presentation of nanoporous oxide formation on titanium alloy.